

**IN THE CLAIMS**

*Please amend the claims as follows:*

1. (Original): A method of manufacturing granular magnetic recording media, comprising sequential steps of:
  - (a) providing a non-magnetic substrate including a surface;
  - (b) forming a layer stack on said surface of said substrate, said layer stack including an outermost granular magnetic recording layer with an exposed nano-scale rough and porous surface;
  - (c) treating said exposed nano-rough and porous surface of said granular magnetic recording layer to provide at least one of:
    - (i) a reduction of said nano-scale roughness and porosity;
    - (ii) increased compositional homogeneity;
    - (iii) increased microstructural homogeneity;
    - (iv) preferential removal of at least one element; and
    - (v) increased grain boundary coverage by a subsequently deposited protective overcoat layer; and
  - (d) forming a protective overcoat layer on the treated surface of said granular magnetic recording layer.
  
2. (Original): The method according to claim 1, wherein:
  - step (b) comprises forming a layer stack including an outermost granular perpendicular magnetic recording layer.

3. (Original): The method according to claim 1, wherein:  
step (b) comprises forming a layer stack including an outermost granular longitudinal magnetic recording layer.

4. (Original): The method according to claim 1, wherein:  
step (c) comprises etching said surface of said granular magnetic recording layer.

5. (Original): The method according to claim 4, wherein:  
step (c) comprises sputter etching said surface.

6. (Original): The method according to claim 5, wherein:  
step (c) comprises sputter etching said surface with ions of an inert gas.

7. (Original): The method according to claim 6, wherein:  
step (c) comprises sputter etching said surface with Ar ions.

8. (Original): The method according to claim 1, wherein:  
step (d) comprises forming a carbon (C)-containing protective overcoat layer.

9. (Original): The method according to claim 8, wherein:  
step (d) comprises forming a diamond-like carbon (DLC) protective overcoat layer.

10. (Original): The method according to claim 9, wherein:

step (d) comprises forming said DLC protective overcoat layer by ion beam deposition (IBD).

11. (Original): The method according to claim 1, wherein:

step (a) comprises providing a non-magnetic substrate comprised of a non-magnetic material selected from the group consisting of: Al, NiP-plated Al, Al-Mg alloys, other Al-based alloys, other non-magnetic metals, other non-magnetic alloys, glass, ceramics, polymers, glass-ceramics, and composites and/or laminates of the aforementioned materials.

12. (Original): The method according to claim 1, wherein:

step (b) comprises forming a layer stack including a granular Co-based alloy magnetic recording layer comprised of a CoPtX alloy, where X = at least one element or material selected from the group consisting of: Cr, Ta, B, Mo, V, Nb, W, Zr, Re, Ru, Cu, Ag, Hf, Ir, Y, O, Si, Ti, N, P, Ni, SiO<sub>2</sub>, SiO, Si<sub>3</sub>N<sub>4</sub>, Al<sub>2</sub>O<sub>3</sub>, AlN, TiO, TiO<sub>2</sub>, TiO<sub>x</sub>, TiN, TiC, Ta<sub>2</sub>O<sub>5</sub>, NiO, and CoO, and wherein Co-containing magnetic grains are segregated by grain boundaries comprising at least one of oxides, nitrides, and carbides.

13. (Original): The method according to claim 1, further comprising a step of:

(e) forming a lubricant topcoat layer on said protective overcoat layer.

14. (Original): The method according to claim 13, wherein:

step (e) comprises forming a layer of a perfluoropolyether material.

Claims 15-25. (Canceled)

26. (Previously Presented): A method of manufacturing granular magnetic recording media, comprising sequential steps of:

- (a) providing a non-magnetic substrate including a surface;
- (b) forming a layer stack on said surface of said substrate, said layer stack including an outermost granular magnetic recording layer with an exposed nano-scale rough and porous surface; and
- (c) etching said nano-rough and porous surface of said granular magnetic recording layer.

27. (Previously presented): The method according to claim 26, wherein:  
step (c) comprises sputter etching said surface.

28. (Previously presented): The method according to claim 27, wherein:  
step (c) comprises sputter etching said surface with ions of an inert gas.

29. (Previously presented): The method according to claim 26, wherein:  
step (b) comprises forming a layer stack including an outermost granular perpendicular magnetic recording layer.

30. (Previously presented): The method according to claim 26, wherein:

step (b) comprises forming a layer stack including an outermost granular longitudinal magnetic recording layer.

31. (Previously presented): The method according to claim 26, wherein:

said granular magnetic recording layer comprises a CoPtX alloy, where X is at least one element or material selected from the group consisting of: Cr, Ta, B, Mo, V, Nb, W, Zr, Re, Ru, Cu, Ag, Hf, Ir, Y, O, Si, Ti, N, P, Ni, SiO<sub>2</sub>, SiO, Si<sub>3</sub>N<sub>4</sub>, Al<sub>2</sub>O<sub>3</sub>, AlN, TiO, TiO<sub>2</sub>, TiO<sub>x</sub>, TiN, TiC, Ta<sub>2</sub>O<sub>5</sub>, NiO, and CoO, and wherein Co-containing magnetic grains are segregated by grain boundaries comprising at least one of oxides, nitrides, and carbides.

32. (Previously Presented): A method of manufacturing granular magnetic recording media, comprising sequential steps of:

- (a) providing a non-magnetic substrate including a surface;
- (b) forming a layer stack on said surface of said substrate, said layer stack including an outermost granular magnetic recording layer with an exposed nano-scale rough and porous surface;
- (c) sputter etching said surface of said granular magnetic recording layer with ions of an inert gas; and
- (d) forming a protective overcoat layer on the treated surface of said granular magnetic recording layer.

33. (Previously presented): The method according to claim 32, wherein:  
step (d) comprises forming a diamond-like carbon (DLC) protective overcoat layer.

34. (Previously presented): The method according to claim 32, wherein:  
step (d) comprises forming said DLC protective overcoat layer by ion beam deposition (IBD).

35. (Previously presented): The method according to claim 32, wherein:  
step (b) comprises forming a layer stack including an outermost granular perpendicular magnetic recording layer.

36. (Previously presented): The method according to claim 32, wherein:  
step (b) comprises forming a layer stack including an outermost granular longitudinal magnetic recording layer.

37. (New) The method according to claim 1, wherein the nano-scale roughness is less than 2.0 Å.

38. (New): The method according to claim 37, wherein the nano-scale roughness is less than 1.5 Å.

39. (New): The method according to claim 26, wherein the nano-scale roughness is less than 2.0 Å.

40. (New): The method according to claim 39, wherein the nano-scale roughness is less than 1.5 Å.

41. (New): The method according to claim 32, wherein the nano-scale roughness is less than 2.0 Å.

42. (New): The method according to claim 41, wherein the nano-scale roughness is less than 1.5 Å.